



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.10/756,622
Filing Date January 12, 2004
Confirmation No. 1635
Inventor.....J. Brett Rolfson
AssigneeMicron Technology, Inc.
Group Art Unit 1763
Examiner George A. Goudreau
Attorney's Docket No. MI22-2482
Customer No. 021567
Title: Ion Implant Lithography Method of Processing a Semiconductor
Substrate

RESPONSE TO JUNE 22, 2005 OFFICE ACTION
TO ACCOMPANY RCE FILING

To: Mail Stop RCE
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

VIA U.S. EXPRESS MAIL

From: Mark Matkin (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
601 West First Avenue, Suite 1300
Spokane, WA 99201-3828

Responsive to the Office Action dated June 22, 2005, Applicant
amends and remarks as follows:

AMENDMENTS

EV 633264275